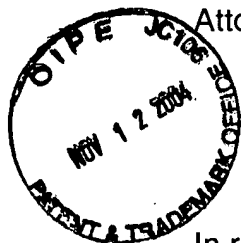


Attorney's Docket No.: 042390P11354D

Patent



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:

Liang, Ted et al.

Examiner: Stevenson, Andre

Application No.: 10/659,961

Art Unit: 2812

Filed: September 10, 2003

For: MASK REPAIR WITH
ELECTRON BEAM-INDUCED
CHEMICAL ETCHING

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

FORMAL DRAWINGS SUBMISSION

Enclosed herewith for submission in the United States Patent and Trademark Office are three (3) sheets of formal drawings for the patent application referenced above.

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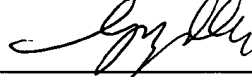
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Respectfully submitted,

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